

97-2 Preliminary Syllabus, Da-Yeh Univ

Information			
Title	半導體製程設備與實習	Serial No. / ID	1753 / EEI4214
Dept.	電機工程學系	School System / Class	大學日間部4年1班
Lecturer	李世鴻	Full or Part-time	專任
Required / Credit	Optinal / 3	Graduate Class	Yes
Time / Place	(四)12 / H203 (五)3 / H355	Language	Chinese

Introduction	
TBA	

Outline	
1. Fundamentals of Vacuum Technology; 2. Plasma; 3. Clean Room; 4. Chemical Gases; 5. Thin Film Deposition Equipments; 6. Thermal Oxidation Furnaces; 7. Etching Techniques and Their Equipments; 8. Photolithography and Its Equipment; 9. Selective Doping Techniques and Their Equipments.	

Prerequisite	
Solis State Electronics	